

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/669,623
Applicants: Christian DUSSARRAT, et al.
Filed: September 24, 2003
Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS
AND SILICON OXYNITRIDE FILMS BY THERMAL
CHEMICAL VAPOR DEPOSITION
TC/A.U.: 1762
Examiner: Bret P. Chen
Docket No.: Serie 5444
Customer No.: 000040582

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ELECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of July 6, 2006 please enter this response:

Amendments to the Claims are reflected in the listing of claims which
begin on page 2 of this paper
Remarks begin on page 10 of this paper.